

L Number	Hits	Search Text	DB	Time stamp
-	93	smith-richard-d.in.	USPAT; US-PGPUB	2003/01/16 09:59
-	13	smith-richard-d.in. and (electrospray electro-spray ESI (electro adj spray))	USPAT; US-PGPUB	2003/01/16 14:20
-	2	tang-keqi.in.	USPAT; US-PGPUB	2003/01/16 10:00
-	4	lin-yuehe.in.	USPAT; US-PGPUB	2003/01/16 10:00
-	736	(battelle adj memorial adj institute).as.	USPAT; US-PGPUB	2003/01/16 10:00
-	16	((battelle adj memorial adj institute).as.) and (electrospray electro-spray ESI (electro adj spray))	USPAT; US-PGPUB	2003/01/16 10:01
-	308	250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))	USPAT; US-PGPUB	2003/01/16 10:26
-	26	(250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same array)	USPAT; US-PGPUB	2003/01/16 14:23
-	81	(250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and reservoir	USPAT; US-PGPUB	2003/01/16 10:04
-	19	((250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same array)) and ((250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and reservoir)	USPAT; US-PGPUB	2003/01/16 10:26
-	17	((250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same array)) and ((250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and reservoir)) and (chip wafer)	USPAT; US-PGPUB	2003/01/16 14:10
-	1	6107628.pn.	USPAT; US-PGPUB	2003/01/16 14:31
-	2	(250/288.ccls. and (electrospray electro-spray ESI (electro adj spray))) and (multi-capillary (multi adj capillary))	USPAT; US-PGPUB	2003/01/16 14:22
-	210	(electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same array	USPAT; US-PGPUB	2003/01/16 14:41
-	1	((electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same array) and (multi-capillary)	USPAT; US-PGPUB	2003/01/16 14:42
-	0	((electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same array) and (CF near2 (rf adj plasma))	USPAT; US-PGPUB	2003/01/16 14:26
-	0	(Improved adj Ionization adj Source adj Utilizing adj2 multi-capillary).ti.	USPAT; US-PGPUB	2003/01/16 14:32
-	0	(Improved adj Ionization adj Source adj Utilizing\$).ti.	USPAT; US-PGPUB	2003/01/16 14:35
-	1	DE-AC06-76RLO1830	USPAT; US-PGPUB	2003/01/16 14:34
-	0	(Improved adj Ionization adj Source\$).ti.	USPAT; US-PGPUB	2003/01/16 14:35
-	104	(electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same (chip wafer)	USPAT; US-PGPUB	2003/01/16 14:46
-	1	((electrospray electro-spray ESI (electro adj spray))) and ((electrospray electro-spray ESI (electro adj spray)) same (chip wafer)) and (multi-capillary)	USPAT; US-PGPUB	2003/01/16 14:53

-	3	(mass adj spectromet\$2) same (multi-capillary)	USPAT; US-PGPUB	2003/01/16 14:53
-	11	(mass adj spectromet\$2) and (multi-capillary)	USPAT; US-PGPUB	2003/01/16 20:54
-	3	multi-capillary adj inlet	USPAT; US-PGPUB	2003/01/16 20:13
-	0	multi-capillary adj inlet	EPO; JPO; DERWENT	2003/01/16 18:57
-	1	multi-capillary and (mass adj spectromet\$2)	EPO; JPO; DERWENT	2003/01/16 19:41
-	64	multi-capillary	EPO; JPO; DERWENT	2003/01/16 20:13
-	0	multi-capillary	IBM_TDB	2003/01/16 19:40
-	0	multicapillary	IBM_TDB	2003/01/16 19:40
-	20	multicapillary	EPO; JPO; DERWENT	2003/01/16 19:41
-	1	multicapillary and (mass adj spectromet\$2)	EPO; JPO; DERWENT	2003/01/16 19:41
-	1	5736740.pn.	USPAT; US-PGPUB	2003/01/16 20:08
-	49	multicapillary	USPAT; US-PGPUB	2003/01/16 20:13
-	6	multicapillary and (mass adj spectromet\$2)	USPAT; US-PGPUB	2003/01/16 20:14
-	1033	(CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)	USPAT; US-PGPUB	2003/01/17 11:13
-	25	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and hydrophob\$5	USPAT; US-PGPUB	2003/01/17 11:02
-	673	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (plasma))	USPAT; US-PGPUB	2003/01/17 11:14
-	7	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and hydrophob\$5) and (((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (plasma))	USPAT; US-PGPUB	2003/01/17 09:29
-	25	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (mass adj spectromet\$2)	USPAT; US-PGPUB	2003/01/17 09:29
-	3	((((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and hydrophob\$5) and (((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (plasma))) and (((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (mass adj spectromet\$2))	USPAT; US-PGPUB	2003/01/17 09:29
-	0	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (hydrophob\$5)	USPAT; US-PGPUB	2003/01/17 09:40
-	7	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (plasma)) and hydrophob\$5	USPAT; US-PGPUB	2003/01/17 11:14
-	5	(CF4 (carbon adj tetrafluoride)) same hydrophob\$5	USPAT; US-PGPUB	2003/01/17 11:16
-	1	4749440.pn.	USPAT; US-PGPUB	2003/01/17 10:54
-	1	4863809.pn.	USPAT; US-PGPUB	2003/01/17 10:55
-	1	6465366.pn.	USPAT; US-PGPUB	2003/01/17 11:02
-	117	(CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)	IBM_TDB	2003/01/17 11:14
-	0	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (plasma)) and hydrophob\$5	IBM_TDB	2003/01/17 11:17
-	59	((CF4 (carbon adj tetrafluoride)) same (silicon chip wafer)) and (CF4 (carbon adj tetrafluoride)) same (plasma))	IBM_TDB	2003/01/17 11:18

-	1	(CF4 (carbon adj tetrafluoride)) same moisture	IBM_TDB	2003/01/17 11:18
-	0	(CF4 (carbon adj tetrafluoride)) same hydrophob\$5	IBM_TDB	2003/01/17 11:18
-	12	(CF4 (carbon adj tetrafluoride)) same hydrophob\$5	EPO; JPO; DERWENT	2003/01/17 11:18
-	0	((CF4 (carbon adj tetrafluoride)) same hydrophob\$5) and (chip wafer)	EPO; JPO; DERWENT	2003/01/17 11:19
-	1	((CF4 (carbon adj tetrafluoride)) same hydrophob\$5) and silicon	EPO; JPO; DERWENT	2003/01/17 11:19